

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Hiroyuki HYODO et al.**

Serial Number: **Not Yet Assigned**

Filed: **September 16, 2003**

Customer No.: **23850**

For: **SOLID MATERIAL GASIFICATION METHOD, THIN FILM FORMATION
PROCESS AND APPARATUSES**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

September 16, 2003

Sir:

In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references is enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge
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Respectfully submitted,
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Enclosures: PTO-1449; References (3)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 031161	Serial No. New Appln.
Applicant(s): Hiroyuki HYODO et al.		
	Filing Date: September 16, 2003	Group Art Unit:

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

FOREIGN PATENT DOCUMENTS

	Document No.	Date	Country	Translation (Yes or No)
_____	AE 5-311446	11/22/93	Japan	Abstract. Cited in the specification.
_____	AF 7-76778	03/20/95	Japan	Abstract. Cited in the specification.
_____	AG 10-298762	11/10/98	Japan	Abstract. Cited in the specification.
_____	AH			
_____	AI			

OTHER DOCUMENTS

_____	AJ	
_____	AK	
Examiner _____		Date Considered _____